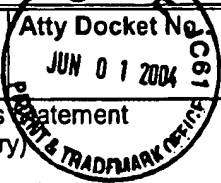


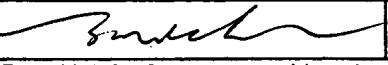
Form PTO-1449 (Modified)		Atty Docket No. P12759C		Serial No.: 10/618,226	
List of Patents and Publications Statement (Use several sheets if necessary)				Applicant: Robert Chau et al.	
				Filing Date: July 11, 2003	



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~	AA 6,020,024	Maiti et al.	427	248.1		
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OTHER ART (Including Author, Title, Date, Pertinent Pages, etc.)	
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	AW
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Examiner 	Date Considered 11/28/04
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EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.